

12-09-05

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: LEE, Ho
Assignee: SAMSUNG ELECTRONICS CO., LTD.
Title: CHEMICAL VAPOR DEPOSITION APPARATUS
Application No.: 10/750,023 Filing Date: December 31, 2003
Examiner: Jeffrie Robert Lund Group Art Unit: 1763
Docket No.: AB-1350 US Confirmation No.: 9344

San Jose, California
December 8, 2005

Mail Stop AF
COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL OFFICE ACTION

Dear Sir:

In response to the Final Office Action having a mailing date of October 11, 2005,
please amend the application as set forth below.

Claim listing begins on page 2 of this paper.

Remarks begin on page 4 of this paper.

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